

Title (en)

FOCUSSED SUBSTRATE ALTERATION.

Title (de)

VERÄNDERUNG EINES SUBSTRATS DURCH EINEN FOKUSSIERTEN STRAHL.

Title (fr)

ALTERATION FOCALISEE D'UN SUBSTRAT.

Publication

EP 0198908 A4 19870302 (EN)

Application

EP 85905575 A 19851025

Priority

- US 66525184 A 19841026
- US 76937085 A 19850826

Abstract (en)

[origin: WO8602774A1] Alteration of a precisely located site on a substrate (35) using apparatus that comprises: a) a focusable ion source (10); b) a lens (22) positioned to focus ions emitted by the source into an ion beam (124); c) a vacuum chamber (30) for containing the substrate site in the path of the ion beam; and d) a directed gas inlet (55) positioned to provide a localized supply of a substance at the site whereby the beam interacts with the substances to cause the alteration localized at the site. Methods of performing the alteration are also disclosed.

IPC 1-7

H01J 37/317

IPC 8 full level

G03F 1/00 (2006.01); **H01J 37/317** (2006.01)

CPC (source: EP)

G03F 1/74 (2013.01); **H01J 37/3178** (2013.01)

Citation (search report)

- [A] EP 0075949 A2 19830406 - HITACHI LTD [JP]
- See references of WO 8602774A1

Designated contracting state (EPC)

AT BE CH DE FR GB IT LI LU NL SE

DOCDB simple family (publication)

WO 8602774 A1 19860509; EP 0198907 A1 19861029; EP 0198908 A1 19861029; EP 0198908 A4 19870302; WO 8602581 A1 19860509

DOCDB simple family (application)

US 8502109 W 19851025; EP 85905574 A 19851025; EP 85905575 A 19851025; US 8502108 W 19851025